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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of

Markus Turtinen, et al.

Serial No.: 10/526,831

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Date: December 18, 2006

Group Art Unit: 2856

Examiner: ---

For: CHARACTERISATION OF PAPER

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Robert C. Faber

Name of applicant, assignee or

Registered Representative

Signature December 18, 2006

Date of Signature

Respectfully submitted,

Robert C. Faber

Registration No.: 24,322

OSTROLENK, FABER, GERB & SOFFEN, LLP

1180 Avenue of the Americas

New York, New York 10036-8403

Telephone: (212) 382-0700

RCF:mjb Enclosures

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OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)						
Jukka Iivarinen (2000) Surface Defect Detection with Histogram-Based Texture Features, Helsinki University of Technology, Laboratory of Computer and Information Science.						
Jukka Iivarinen, et al. (1998) An Adaptive Texture and Shape Based Defect Classification, Pattern Recognition, Proceedings, PP. 117-122.						
Timo Ojala, et al., Gray Scale and Rotation Invariant Texture Classification with Local Binary Patterns, IEEE Transactions on Pattern Analysis and Machine Intelligence, Vol. 24, No. 7.						
Examiner	ner Date Considered					
EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.						